

## Publikationen

(2011): Conductivity and Charge Trapping After Electrical Stress in Amorphous and Polycrystalline Al<sub>2</sub>O<sub>3</sub>-Based Devices Studied With AFM-Related Techniques. In: IEEE Transactions on Nanotechnology, vol. 10, no. 2, pp. 344-351.

(2009): Crystallization and silicon diffusion nanoscale effects on the electrical properties of Al<sub>2</sub>O<sub>3</sub> based devices. In: Microelectronic Engineering, vol. 86, no. 7-9, pp. 1921-1924.

(2007): Influence of the manufacturing process on the electrical properties of thin (< 4 nm) Hafnium based high-k stacks observed with CAFM. In: 18th European Symposium on Reliability of Electronic Devices, Failure Physics and Analysis (ESREF), Arcachon, Frankreich.

(2007): Influence of the manufacturing process on the electrical properties of thin (< 4 nm) Hafnium based high-k stacks observed with CAFM. In: Microelectronics Reliability, vol. 47, no. 9, pp. 1424-1428.